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INSTHE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

Akinobu Sato, et al.

Serial No.:

10/573,942

Filing Date:

March 29, 2006

Title:

Solid surface smoothing

method and apparatus therefor

Conf. No.

5411

Examiner: Rodney Glenn McDonald

Art Unit: 1753

September 11, 2007 San Francisco, California

Mail Stop Amendment Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to the duty of disclosure set forth in 37 CFR § 1.56, Applicants respectfully submit the following information disclosure statement.

The undersigned certifies that each of the following references was contained in a communication from the EPO in a counterpart foreign application not more than three months prior to the filing of this statement.

The disclosed references are:

PCT Application Publication No. WO 03/048407, Epion Corp., dated 6-12-2003.

PCT Application Publication No. WO 01/41181, Epion Corp., dated 6-7-2001.

Yamada, I., et al.; "Materials processing by gas cluster ion beams," Materials Science & Engineering Reports, Elsevier Sequoia, S.A., Lausanne, CH, Vol. 34, no. 6, Oct. 30-01, pp. 231-295.

Docket: NAA237

Applicants respectfully request that the Examiner initial the cited references shown on the enclosed form PTO-1449 and that the references be made of record in the present application.

Respectfully submitted,

Larry Menderhall Reg. No. 38,555

601 California St., Suite 1111 San Francisco, CA 94108-2805

Telephone: (415) 989-8080 Facsimile: (415) 989-0910

Enc. PTO Form 1449

Cited references (3) Return receipt postcard Certificate of Mailing Under 37 CFR 1.8

I certify that this Information Disclosure Statement and all enclosed materials are being deposited with the United States Postal Service on September 11, 2007 with sufficient postage as first class mail in an envelope addressed to Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Jean C. Reed

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		WO 03/048407	6-12-2003	PCT, Epion	Corp.			
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		Reports, Elsevier Seque	oia, S.A., Lausar	nne, CH, Vol.	34, no. 6, Oct. 30-01, pp.	231-295.		
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